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Title: Chemical Vapor Deposition Methods of Forming Barium Strontium Titanate Comprising Dielectric Layers

Assignee: Micron Technology, Inc.

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INFORMATION DISCLOSURE STATEMENT

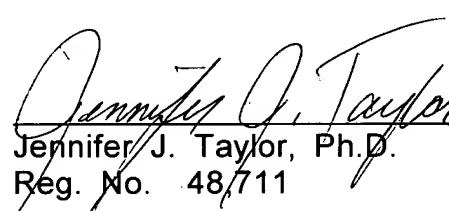
References – See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: May 28, 2003

By:


Jennifer J. Taylor, Ph.D.
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